

nev's Docket No. 5308-395

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Michael John O'Loughlin et al.

Confirmation No.: 1454 Group Art Unit: 1765

Serial No.: 10/790,406

Examiner: Nadine Georgianna Norton

Filed: March 1, 2004 Examin For: Reduction of Carrot Defects in Silicon Carbide Epitaxy

Date: July 7, 2005

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT FOR INTERNATIONAL SEARCH REPORT

Sir:

Attached is a Supplemental Form PTO-1449 listing documents cited in the International Search Report for the corresponding International Application Number PCT/US2004/038895. Each document listed on the attached PTO-1449 was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Statement. A copy of any listed foreign patent document and/or non-patent literature, including the Search Report, is enclosed. A copy of any listed U.S. patent and/or U.S. patent application publication is not provided herewith in accordance with the amendment by the U.S. Patent and Trademark Office of requirements under 37 C.F.R. § 1.98(a)(2)(ii) effective October 21, 2004.

It is requested that these documents be considered by the Examiner and officially made of record in accordance with the provisions of 37 C.F.R. §1.56 and Section 609 of the MPEP.

No fee is believed due; however, the Commissioner is hereby authorized to charge any deficiency or credit any refund to Deposit Account No. 50-0220.

Respectfully submitted,

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Shekna L Donnelly

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Substitute	form 1449A/PTO	70	V	Complete if Known		
				Application Number	10/790,406	
INFORM	IATION DISCLOSUR		1 1 2005	NF ling Date	March 1, 2004	
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		VE.		Group Art Unit	1765	
(use as m	any sheets as necessary)	To TH	ANGARE	Examiner Name	Nadine Georgianna Norton	
Sheet	1 of	1		Attorney Docket Number	5308-395	

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